## Plasma-enhanced atomic layer deposition for plasmonic TiN (Erratum)

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Proceedings Volume 9909, Nanophotonic Materials XIII; 99190N (2016) https://doi.org/10.1117/12.2573754

Online Publication Date: 3 October 2016 Erratum Published: 12 May 2020

A revised version of this manuscript was published on 12 May 2020. Details of the revision are as follows:

Change 1: Table 1, Plasma 2 - gases were listed in the wrong order and so were flipped.

Change 2: Equation 1 - an incorrect negative sign was switched to a positive sign in the denominator of the Lorentz component.

Nanophotonic Materials XIII, edited by Stefano Cabrini, Gilles Lérondel, Adam M. Schwartzberg, Taleb Mokari, Proc. of SPIE Vol. 9919, 991918 © 2016 SPIE · CCC code: 0277-786X/16/\$18 · doi: 10.1117/12.2573754